

## Design Rules

- ① Metal & Diffusion have min<sup>m</sup> width & Spacing of  $4\lambda$
- ② Contacts are  $2\lambda \times 2\lambda$  and must be surrounded by  $1\lambda$  on the layers above and below.
- ③ PolySi uses a width of  $2\lambda$  where
- ④ PolySi overlaps diff. by  $2\lambda$  ~~above~~ a transistor is desired and has a spacing of  $\lambda$  away where no transistor is desired.
- ⑤ PolySi and contacts have a spacing of  $3\lambda$  from other ~~polySi~~ polySi or contacts
- ⑥ N-well surrounds pMOS transistors  
by  $6\lambda$  and avoids nMOS transistor  
by  $6\lambda$

## Design Rules

① Contact cut  $\rightarrow 2\lambda \times 2\lambda$

② Contact cut to diffusion  $\rightarrow \lambda$

③ diffusion to depletion Implant  $2\lambda$

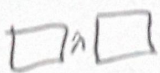
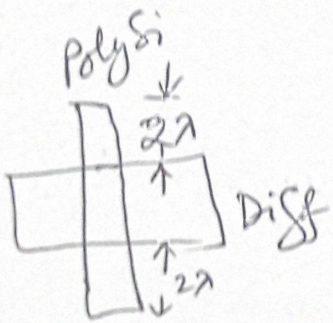
Metal length  $= 4\lambda$

Metal to Metal distance  $\Rightarrow 4\lambda$

N-well to p-diffusion  $\Rightarrow 6\lambda$

N-well to n-diff  $\Rightarrow 6\lambda$

poly Si width  $\Rightarrow 2\lambda$



- \* Contact to Contact  $\lambda$  distance Min<sup>m</sup>  $2\lambda \times 2\lambda$
- \* Metal 1, Metal 2 use  $\overline{\text{top}}$ ,  $\overline{\text{top}}$  - short  $2\lambda \times 2\lambda$
- \* Poly, Poly overlap  $\overline{\text{top}}$  short; Diff, Diff short  $2\lambda$